

ABSTRACT

**LASER PROCESSING METHOD AND APPARATUS
FOR FORMING A LAYER OF MATERIAL**

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A method and apparatus for forming a layer of material onto a substrate at a target region is provided. A laser beam is directed onto a material source through the substrate so that to generate an induced material from the material source. The induced material then deposits onto the substrate to form the layer of material. The laser beam removes the layer of the material deposited outside the target region. The apparatus comprises a laser source for generating a laser beam, and an optic system for directing the laser beam into a substrate. The laser beam generates an induced material from the material source to deposit onto the substrate to form the layer of material, and the laser beam removes the layer of the material deposited outside the target region.

(Fig. 2C)